

1751  
JFW

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of Applicants:

Date: January 17, 2005

Bietsch, et al.

Group Art Unit: 1751

Serial No.: 10/081,860

Examiner: Lynette T Umez Eronini

Filed: February 22, 2002

Docket No.: CH920010003US1

For: *SELECTIVE ETCHING OF SUBSTRATES WITH CONTROL OF THE ETCH PROFILE*

Assistant Commissioner for Patents

Post Office Box 1450

Alexandria, VA 22313-1450

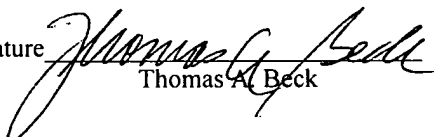
IN THE DRAWINGS:

Please review and enter the enclosed six sheets of formal drawings into the above-identified application.

Respectfully Submitted,

Thomas A. Beck  
Registration Number 20,816  
26 Rockledge Lane  
New Milford, CT 06776

I hereby certify that this paper is being deposited with the United States Postal Service, first class mail, postage prepaid, on the date indicated below in an envelope addressed to the Commissioner of Patents and Trademarks, Post Office Box 1450, Alexandria, VA 22313-1450

Signature  Date: January 25, 2005  
Thomas A. Beck